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CONFIRMATION NO. 7971

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| SERIAL NUMBER 10/696,775 | FILING OR 371(c) DATE 10/30/2003 RULE | CLASS 438 | GROUP ART UNIT 2813 | ATTORNEY DOCKET NO. 032076 |
| APPLICANTS Masayuki Furuhashi, Kawasaki, JAPAN; Toshifumi Mori, Kawasaki, JAPAN; Young Suk Kim, Kawasaki, JAPAN; Takayuki Ohba, Kawasaki, JAPAN; Ryou Nakamura, Kawasaki, JAPAN; | | | | |
| ** CONTINUING DATA ***** ** FOREIGN APPLICATIONS ***** JAPAN 2002-317456 10/31/2002 | | | | |
| IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 02/06/2004 | | | | |
| Foreign Priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged _____ Examiner's Signature _____ Initials _____ | | STATE OR COUNTRY JAPAN | SHEETS DRAWING 33 | TOTAL CLAIMS 25 |
| | | | | INDEPENDENT CLAIMS 6 |
| ADDRESS 38834 | | | | |
| TITLE Method for fabricating a semiconductor device including the use of a compound containing silicon and nitrogen to form an insulation film of SiN, SiCN or SiOCN | | | | |
| FILING FEE RECEIVED 1248 | FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: | | <input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit | |

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